

ABSTRACT

This substrate processing apparatus includes: a boat including a plurality of slots configured to hold at least one substrate; a process furnace configured to process the at least one substrate held in the boat; a boat elevator configured to raise and lower the boat; a transfer device configured to transfer the at least one substrate between a plurality of carrier in which the at least one substrate is stored and the boat; and a controller configured to be capable of controlling the boat elevator and the transfer device, wherein the controller is configured to set a plurality of positions at which the transfer device transfers the at least one substrate to the boat elevator, and perform a selection of the plurality of positions to minimize a number of shifts among the plurality of positions of the boat elevator or a total time taken during the shifts in each of an operation of the transfer device to load the at least one substrate into the boat until the at least one substrate is loadable into the process furnace from the plurality of carriers and an operation of the transfer device to unload the at least one substrate processed in the process furnace from the boat to the plurality of carriers.

FIG. 4